

### In the Claims

Please amend Claims 1, 7, and 19 as indicated in the VERSION WITH MARKINGS TO SHOW CHANGES MADE to read as shown below.

1. (Twice Amended) A method of using a recording device that records a pressure in a vacuum device that is not a silicon wafer processing device, the vacuum device enabled to couple to a fetus, comprising:

detecting a pressure in the vacuum device, the vacuum device enabled to couple to a fetus;

recording the pressure in the vacuum device; and

storing a record of the pressure.

7. (Twice Amended) A method of using a recording device to record a pressure in a vacuum device that is not a silicon wafer processing device, the vacuum device enabled to couple to a fetus, comprising:

placing the vacuum device on a fetus, the space between the fetus and the vacuum device having a pressure;

initiating a vacuum pressure in the suction device;

detecting the vacuum pressure in the suction device; and

automatically recording the vacuum pressure in the suction device.

19. (Twice Amended) A method of using a recording device to record a pressure in a vacuum device that is not a silicon wafer processing device, the vacuum device enabled to couple to a fetus, comprising:

coupling the recording device to the vacuum device, the vacuum device enabled to couple to a fetus; and

recording the pressure so that a record may be produced therefrom.